

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	) Confirmation No.: 1187
Koichiro TANAKA et al.	) Examiner: Sang Y. Paik
Serial No.: 10/579,238	) Group Art Unit: 3742
Filed: May 12, 2006	)
For: LASER IRRADIATION APPARATUS	)
AND LASER IRRADIATION METHOD	)

**AMENDMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

In response to the Official Action dated February 17, 2010, please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims, which begins on page 2 of this paper.

**Remarks** begin on page 8 of this paper.